

International Application No.: PCT/JP2004/009315  
U.S. Patent Application No.: Unknown  
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**IN THE ABSTRACT:**

Please replace the Abstract of the Disclosure originally filed with the above-identified patent application with the following new Abstract of the Disclosure:

ABSTRACT OF THE DISCLOSURE

A compact, high-sensitivity acceleration sensor that is prevented from being affected by factors other than acceleration, such as a change in temperature, has a bimorph acceleration-sensor element including first and second resonators attached to opposite sides of a base plate with respect to a direction in which acceleration is applied. One longitudinal end of the acceleration-sensor element is fixed such that the first and second resonators bend in the same direction in response to the acceleration. Changes in frequency or changes in impedance in the first and second resonators caused by the bending of the acceleration-sensor element are differentially detected in order to detect the acceleration. The acceleration-sensor element is bendable about a central bending plane in response to the acceleration, the central bending plane being positioned at a central portion of the base plate with respect to the application direction of acceleration. A vibrating section of each of the first and second resonators is disposed close to the fixed end of the acceleration-sensor element.